



NVM-Series Surface Profiling System

NVM-Series is automated high speed measurement tool for in-line process monitor for high density, micro-via substrates used in flip-chip package.

Automated align & auto focus functions enable automatic measurement and to show & save data result the data result on PC and statistical analysis

Noncontact, Large area, and High precision 3D Measurement tool.

Specification

Measuring method	White-Light Scanning Interferometry(WSI), Phase Shift Interferometry(PSI)
F.O.V Lens	4 Position Motorized Turret Addition F.O.V Available (Option)
Scanning Range	MAX 270um (PZT Scanning)
Scanning Velocity	12um/sec (1x~5x user-selectable)
Vertical Resolution	WSI : < 0.5nm / PSI : < 0.1nm
Lateral Resolution	0.2 ~ 4um (Objective Lens Dependent)
Illumination	White-light LED Illumination
Tip / Tilt	Probe Tip/Tilt $\pm 6^\circ$ Motorized
Interferometric Objectives	5Lens Available (Motorized Turret)
Step Height Repeatability	0.1% @1 σ (Standard Sample 8um)
X,Y Stroke	Customization (Motorized)
Z Stroke	50mm (Motorized)
Stage Size	Customization

Option

F.O.V Lens	0.55x, 0.75x, 1.0x, 1.5x, 2.0x (Selectable)
Interferometry Objectives	2.5x, 5x, 10x, 20x, 50x, 100x (Selectable)
Vaccum Stage	Option



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